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Flexible and Printable Graphene Electronics

Guest Editor:

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Message from the Guest Editor

Since its discovery in 2004, graphene has revolutionized the field of nanoscience and nanotechnology, and it further continues to do so. Graphene brought the first fundamental concept of linear band structure in solids that is the key to almost all of its glories. The subsequent discovery of the chemical vapor deposition of graphene was the first in its large-scale manufacturing that opened up the scalability of this material and its associated devices.

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Message from the Editor-in-Chief

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